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**WAFER MANAGEMENT SYSTEM AND METHODS FOR MANAGING WAFERS**Abstract of the Disclosure

5 A wafer management system has a first stationary wafer  
storage system (100) with a first buffer (110) for  
storing a plurality of wafers in slots, a first load-and-  
unload station (115) for transferring the wafers between  
the first buffer (110) and intra-bay pods (120, 130)  
10 assigned to a first bay (160), and a second load-and-  
unload station (184) for transferring wafers between the  
first buffer (110) and further pods (520, 530). The  
storage system (100) and the bay (160) form a single  
unit. Multiple units are linked together by tracks (500).

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